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Exposure control circuit, 73···Laser length measuring machine, 74···Distribution circuit, 75a, 75b···Buffer memory, 76···Selection circuit.

The present invention permits correction of the  
5 pattern data to be performed in the phase of preparing  
the pattern data. The pattern data generation and  
storage speed may be kept at one tenth through one  
hundredth the speed for reading and writing the data.  
So the size of the circuit can be reduced to one tenth  
10 through one hundredth that in the case where pattern  
data is corrected. Thus, the cost reduction achieved  
by the present invention provides a drastic effect.